

L Number	Hits	Search Text	DB	Time stamp
-	311	CMOS adj imager	USPAT; US-PGPUB	2003/06/09 16:05
-	52440	polysilicon	USPAT; US-PGPUB	2003/06/09 17:24
-	60961	chemical adj vapor adj deposit\$3	USPAT; US-PGPUB	2003/06/09 17:24
-	59268	CVD	USPAT; US-PGPUB	2003/06/09 17:24
-	78805	sputtering	USPAT; US-PGPUB	2003/06/09 17:24
-	1775	polysilicon same ((chemical adj vapor adj deposit\$3) or CVD) same sputtering	USPAT; US-PGPUB	2003/06/09 17:25
-	568	(polysilicon same ((chemical adj vapor adj deposit\$3) or CVD) same sputtering) and @PY<1999	USPAT; US-PGPUB	2003/06/09 17:29
-	237407	capacitor	USPAT; US-PGPUB	2003/06/09 17:30
-	214	((polysilicon same ((chemical adj vapor adj deposit\$3) or CVD) same sputtering) and @PY<1999) and capacitor	USPAT; US-PGPUB	2003/06/09 17:30